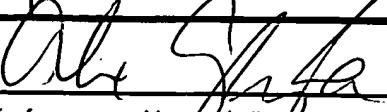


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				Alessandro Callegari, et al.			
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U.S. PATENT DOCUMENTS							
EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
<i>AC</i>		5,312,565	11/01	Misra, et al.			
		6,037,003	3/14/00	Gordon, et al.			
		5,728,222	3/17/98	Barbee, et al.			
		5,648,113	7/15/97	Barbee, et al.			
		5,540,777	7/30/96	Barbee, et al.			
<i>AC</i>		5,431,734	7/11/95	Chapple-Sokol, et al.			
<i>AC</i>		4,097,314	6/27/78	Schlesier, et al.			
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		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION YES NO
OTHER DOCUMENTS <i>(Including Author, Title, Date, Pertinent Pages, Etc.)</i>							
<i>AC</i>		<u>Eble, R., et al., "Low Temperature Aluminum Oxide Deposition Using Trimethylaluminum", Journal of Electronic Materials, Vol. 12, No. 3, pp. 587-601 (1983);</u>					
<i>AC</i>		<u>Kim, J.S., et al., "Fabrication of Aluminum Oxide Thin Films by a Low-Pressure Metalorganic Chemical Vapor Deposition Technique", App. Phys. Lett., 62(7), February 15, 1993;</u>					
EXAMINER <i>Alv. Ghosh</i>				DATE CONSIDERED <i>9/27/05</i>			
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FOREIGN PATENT DOCUMENTS							
		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION
							YES
OTHER DOCUMENTS <i>(Including Author, Title, Date, Pertinent Pages, Etc.)</i>							
<i>AC</i>			Fournier, J., et al., "Preparation and Characterization of Thin Films of Alumina by Metal-Organic Chemical Vapor Deposition", <u>Mat. Res. Bull.</u> , Vol. 23, pp. 31-36, 1988;				
<i>AC</i>			Klein, T.M., et al. "Evidence of Aluminum Silicate Formation During Chemical Vapor Deposition of Amorphous Al ₂ O ₃ Thin Films on Si (100)", <u>Applied Physics Letters</u> , Vol. 75, No. 25, pp. 4001-4003, 1999;				
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<i>Alex Gherardi</i> <i>9/27/01</i>							

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FOREIGN PATENT DOCUMENTS								
		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
							YES	NO
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AC			Lo, S.-H, et al., "Quantum-Mechanical Modelling of Electron Tunneling Current From the Inversion Layer of Ultra-Thin-Oxide nMOSFET's", <u>IEEE Electron Device Letters</u> , Vol. 18, No. 5, pp. 209-211, May 1997;					
AC			Mutoh, H., et al., "Multilayer Metallization with Planar Interconnect Structure Utilizing CVD Al ₂ O ₃ Film", <u>J. Electrochem. Soc.: SOLID-SCIENCE AND TECHNOLOGY</u> , Vol. 12, No. 7, pp. 987-992, July 1975; and					
EXAMINER			DATE CONSIDERED					
 <i>Alessandro Callegari</i>								

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